

What is claimed is:

1. A method of polishing a workpiece in a polishing apparatus, comprising:
  - 5 conditioning a polishing surface by a contact-type dresser for initial conditioning before starting using said polishing surface;
  - polishing a workpiece by bringing said workpiece into contact with said polishing surface after said conditioning; and
  - 10 dressing said polishing surface after said polishing by a noncontact-type dresser for removing ground-off particles of said workpiece.
2. A method according to claim 1, wherein said noncontact-type dresser and said contact-type dresser are provided in said polishing apparatus.
- 15 3. A method according to claim 1, wherein said noncontact-type dresser comprises a plurality of fluid jet nozzles for ejecting fluid jets.
4. A method according to claim 3, wherein the pressure of each of said nozzles is variable.
- 20 5. A method according to claim 1, wherein said contact-type dresser comprises a diamond dresser.
6. A method according to claim 1, wherein said polishing surface is dressed by said 25 contact-type dresser before said dressing of said polishing surface by said noncontact-type dresser.

7. A method according to claim 1, wherein said noncontact-type dresser is angularly movable to a standby position located outwardly of said polishing surface.

8. A method according to claim 7, wherein said contact-type dresser is angularly movable to a standby position located outwardly of said polishing surface.

9. A method of polishing workpieces in a polishing apparatus, comprising:  
attaching a member having a polishing surface to a table;  
conditioning said polishing surface by a contact-type dresser for initial conditioning  
before starting using said polishing surface;

polishing workpieces repeatedly by bringing each of said workpieces into contact with  
said polishing surface after said conditioning while supplying an abrasive liquid in said  
polishing; and

dressing said polishing surface between said polishing of said workpieces by a  
noncontact-type dresser for removing ground-off particles of said workpieces.

10. A method according to claim 9, further comprising holding said each of said  
workpieces by a vacuum.

20           11. A method according to claim 9, wherein said noncontact-type dresser comprises  
a plurality of fluid jet nozzles for ejecting fluid jets.

12. A method according to claim 11, wherein the pressure of each of said nozzles is  
variable.

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13. A method according to claim 9, wherein said contact-type dresser comprises a  
diamond dresser.

14. A method according to claim 9, wherein said polishing surface is dressed by said contact-type dresser before said dressing of said polishing surface by said noncontact-type dresser.

- 5        15. A method of polishing a workpiece in a polishing apparatus, comprising:  
            attaching a member having a polishing surface to a table;  
            conditioning said polishing surface for initial conditioning before starting using said  
            polishing surface;  
            polishing a workpiece by bringing said workpiece into contact with said polishing  
10     surface after said conditioning; and  
            dressing said polishing surface after said polishing for removing ground-off particles  
            of said workpiece.

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